





OPTICAL PROFILER



Offering more than 25 Years of Material Science Experience



RESEARCH AND CONSULTATION

Extensive range of research content such as brochures, application notes, publications, and videos.



EXPERT ASSISTANCE

Dedicated Profilometry experts happy to guide you through any question or project request.



CUTTING EDGE INNOVATION

At Nanovea we are always developing cutting edge technologies and standards. We innovate our instruments so that you can innovate your own products.



PRE AND POST INSTALLATION SUPPORT

Full walk-through and guide to make sure the instrument is installed perfectly. Dedicated support team to help you after your instrument has been installed.

INSTRUMENTS



ST400 OPTICAL PROFILER

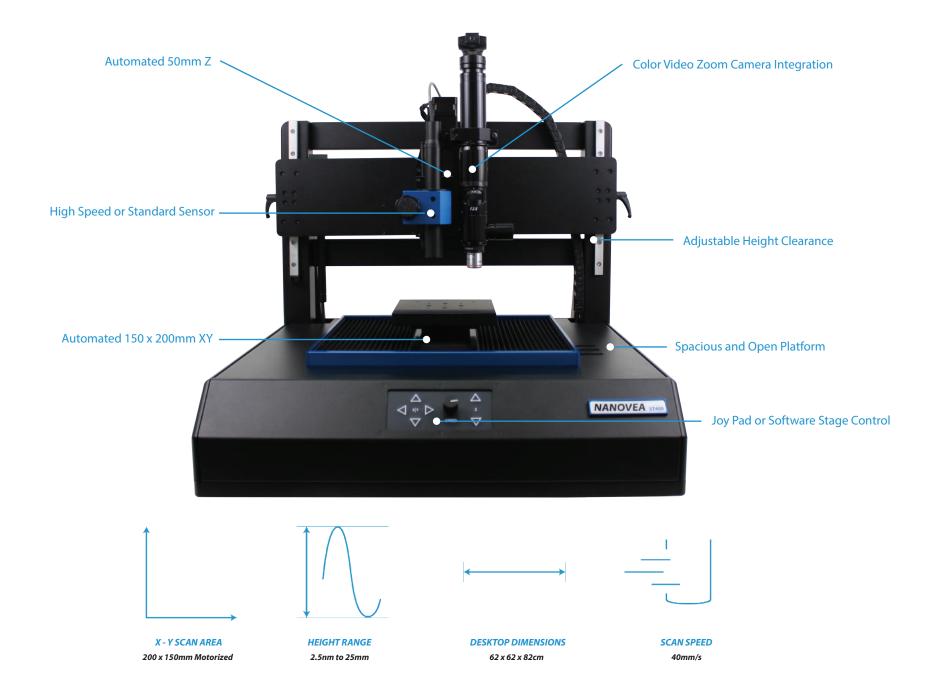
- 200 x 150mm XY stages
- Video imaging integration
- Ideal for wide range of samples with varied geometries
- Chromatic confocal sensors w/ speed up to 200 times faster
- Rotational stage parallel or perpendicular to the testing plate
- Height sample clearance up to 200mm



Standard Sensor High Speed Sensor



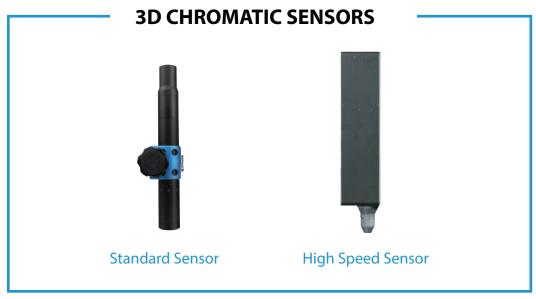
THE STANDARD FOR PROFILOMETRY



ST500 LARGE AREA OPTICAL PROFILER

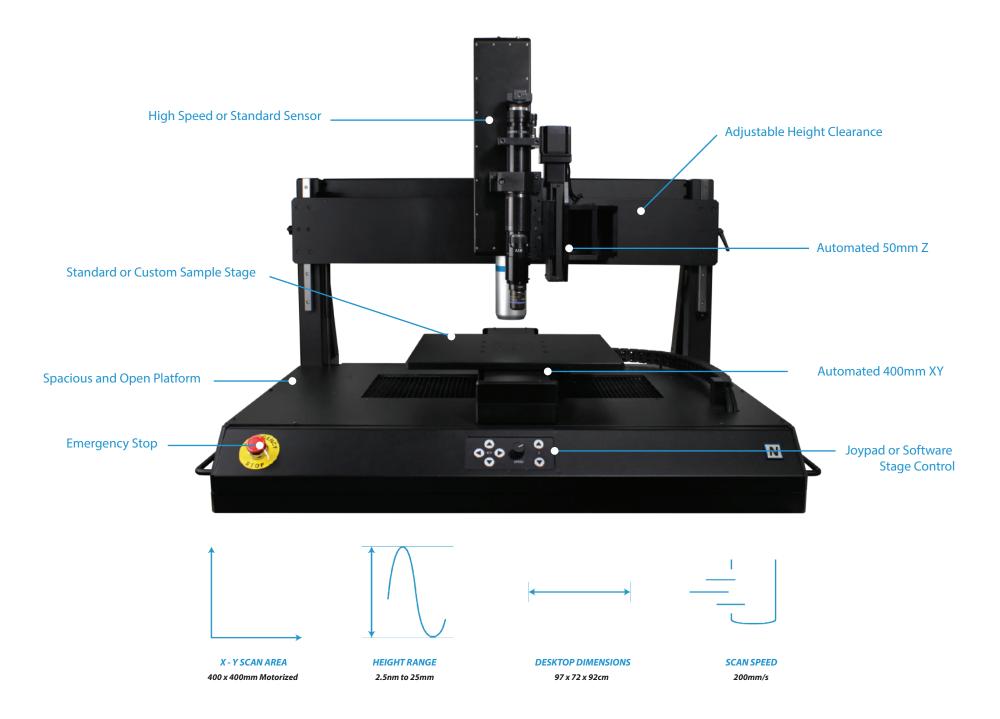
- High speed large area measurement w/ high speed sensor
- 400 mm XY axis travel with a maximum speed up to 200 mm/s
- Video zoom camera to provide automated functions
- Measurements with a user friendly desktop platform







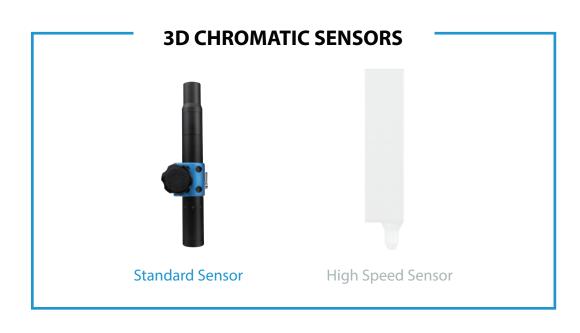
HIGH SPEED AND LARGE AREA MEASUREMENT

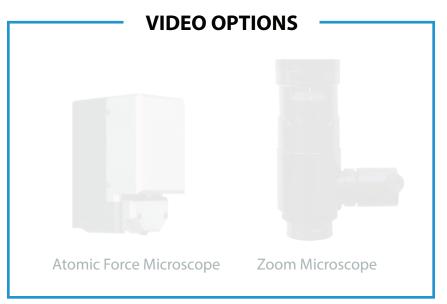


JR25 PORTABLE OPTICAL PROFILER

- First truly portable non contact profilometer
- Weight less than 5.5 kg
- Lab quality results on the go
- Measurement capabilities up to 25mm x 25mm
- Able to measure samples at difficult angles
- Possible integration into automated robot arms and other equipment







LABORATORY QUALITY RESULTS IN ANY LOCATION

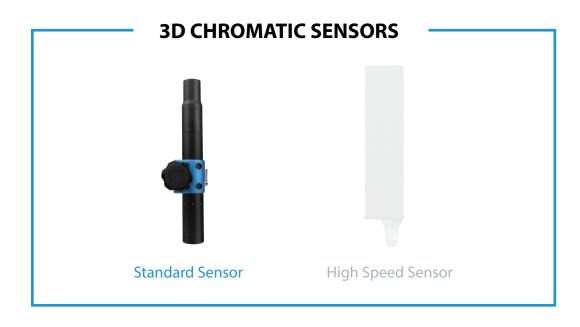


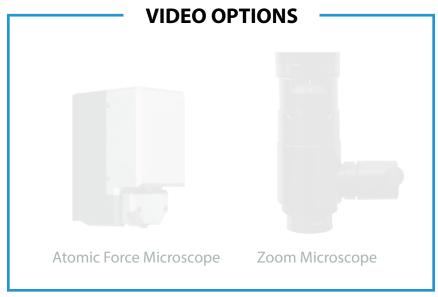


PS50 COMPACT OPTICAL PROFILER

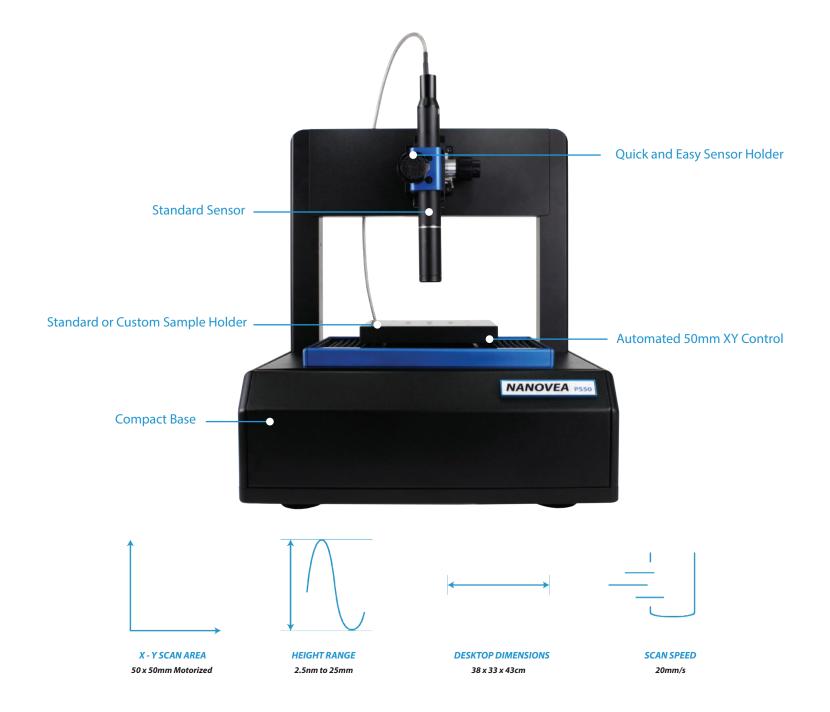
- Most advanced compact profilometer
- Small and simple footprint
- Measurement capabilities up to 50mm x 50mm
- All testing capabilities in compact version







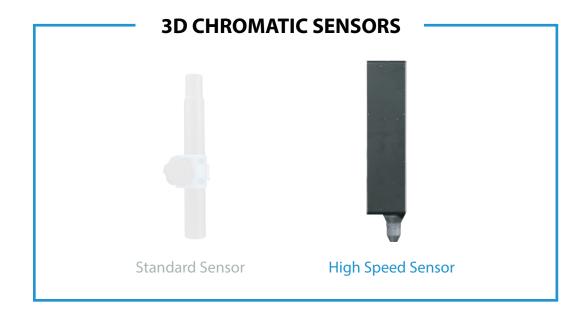
MOST ADVANCED COMPACT BENCHTOP

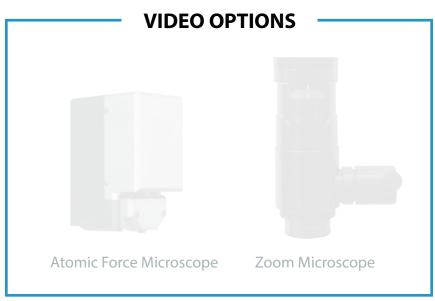


JR100 PORTABLE & HIGH SPEED OPTICAL PROFILER

- Fast measurement (without stitching) using a 100 mm XY axis travel
- Z stage allows setup of measurements at various starting heights
- A high speed sensor gives ultra fast measurements at 382,000 points per second.
- Powerful for quality control







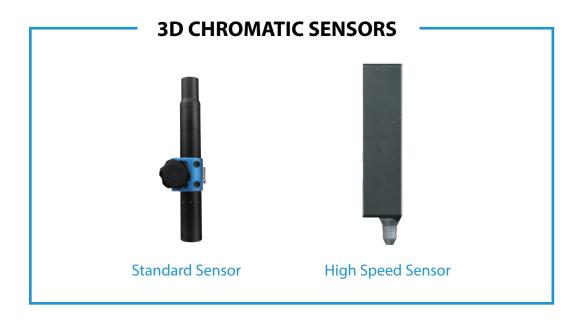
PORTABILITY AND HIGH SPEED



AFMPRO OPTICAL PROFILER

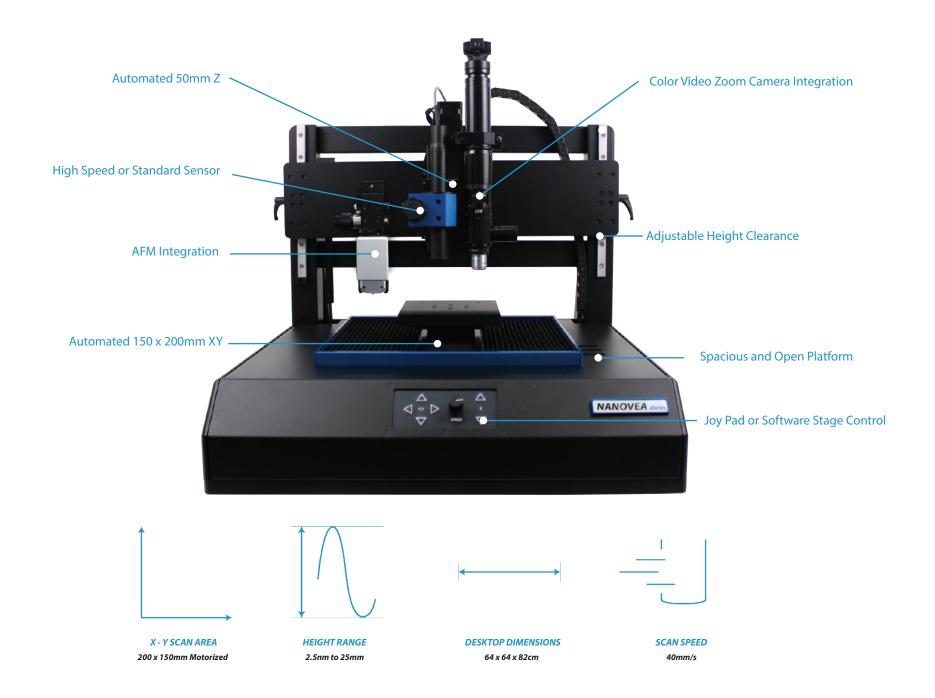
- 150 x 200mm XY stages and an adjustable height clearance of up to 140mm
- High magnification microscopy
- AFM expands the 3D capabilities into the sub nanometer range
- AFM gives the best lateral accuracy compared to optical techniques
- Easy to select zones on the video to be scanned





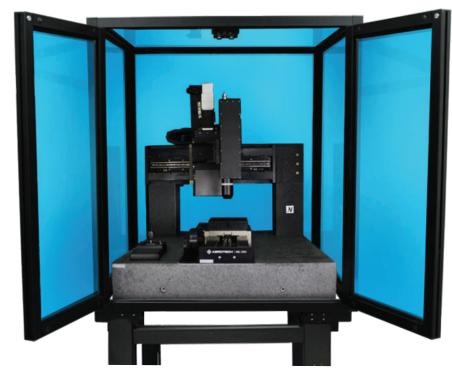


OPTICAL PROFILER WITH AFM MODULE



HS2000 ZERO NOISE & FLATNESS OPTICAL PROFILER

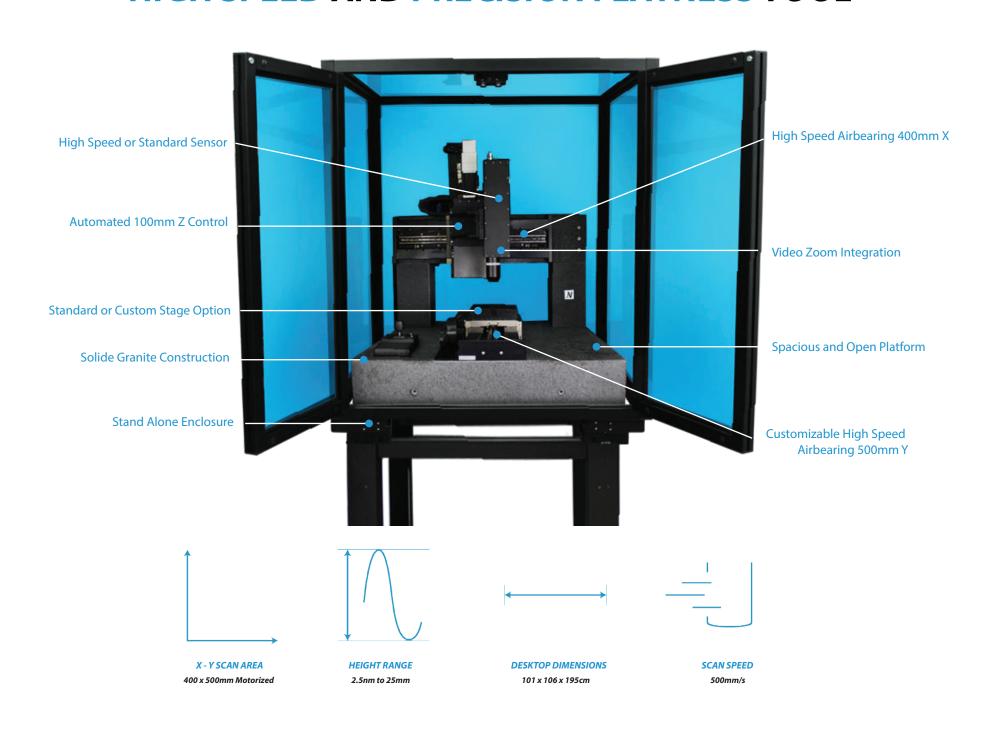
- Granite base and air bearing stages provide superior stability
- Flatness of <1 micron over 500mm with no software correction needed
- Automated inspection for quality control
- Workstation included to create fully contained stand alone instrument
- Excellent for roughness measurements, combined with advanced automation features



Standard Sensor High Speed Sensor



HIGH SPEED AND PRECISION FLATNESS TOOL



TECHNIQUE

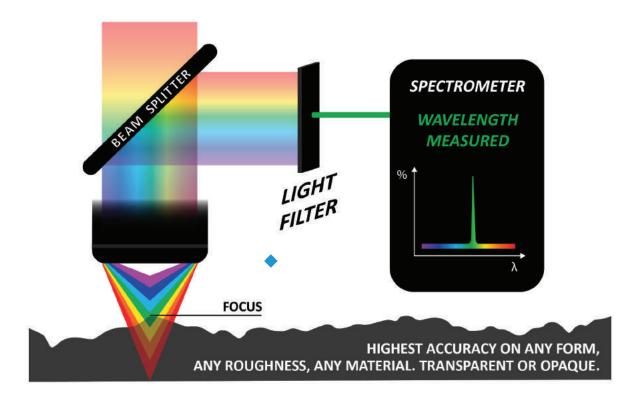


CHROMATIC CONFOCAL

Chromatic Confocal technique uses white light that passes through a series of lenses with high degree of chromatic abberations. Each wavelength will focus at a different distance creating the vertical measurement range. When a surface of interest is within the measurement range a single wavelength of the white light will be in focus while all others will be out of focus.



Only the focused wavelength will pass through the pin hole filter to reach the CCD spectrometer. The physical wavelength measured corresponds to a vertical position.



◆ NO USE OF COMPLEX ALGORITHIMS

♦ NO LEVELING REQUIRED

LATERAL RESOLUTION VS ACCURACY

THE PROBLEM WITH OTHER TECHNIQUES



THEM

Camera pixel size or display resolution size are often used as lateral resolution to impress clients. For these, complex algorithms used to determine what is actually in focus gives a very different story of actual accuracy especially on complex surfaces.

Chromatic Confocal lateral accuracy is determined by physics and directly related to the spot size of the light.

LASER SCANNING CONFOCAL MICROSCOPE

WHITE LIGHT CHROMATIC CONFOCAL

High Speed Sensor 384000 Hz

| LASER RADIATION | Laser Light Health Hazard Need for care of reflected light | | _ | SAFE WHITE LIGHT |
|-----------------|---|---|---|---|
| | Change in wavelength of laser light affects results on the same sample | H | | UNIFORM BROAD WHITE LIGHT SPECTRUM No effect of light intensity on results |
| Height & la | Non significant "display resolution" teral accuracy fixed by objective used Complex accuracy calculations | | _ | INDEPENDENT LATERAL & HEIGHT ACCURACY Any scan area at selected height accuracy |
| | lpha blending algorithms to combine data for complex accuracy calculation | H | _ | NO ALGORITHMS Physical Wavelength Measured = Accurate Height |
| Inaccurate s | Limited fixed field of view titching algorithms for larger surfaces | | | NO STITCHING Continuous scanning of larger surfaces Accuracy constant across any measurement size |
| | Data Acquisition speed 7900 Hz | | | 50x FASTER High Speed Sensor 384000 Hz |

SCANNING A COIN

50x OBJECTIVE vs HIGH SPEED SENSOR (950 μm)

LATERAL ACCURACY

For 50x objective (370 x 277 μ m)

- ± 2% of measuring value
- ± 2% x 370 μm
- ≈ 15 µm

w/ stitching algorithms >> 15 μm

Step size:

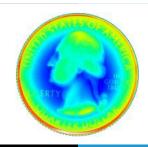
= 5 µm

ULTIMATE LIMIT: **0.9 μm**

3x BETTER LATERAL ACCURACY

HEIGHT ACCURACY

 $\approx 0.2 + L/100 \mu m$ $\approx 0.2 + 950/100 \mu m$ $\approx 9.7 \mu m$



950 μm range

≈ 0.6 µm

ULTIMATE LIMIT: 0.014 μm

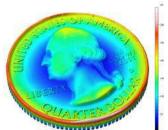
16x BETTER HEIGHT ACCURACY

AREA TESTED

STITCHING REQUIRED

scans (25 x 25 mm) 25 000 μ m / 370 μ m x 25 000 μ m / 277 μ m 68 x 91

= 6188 scans



NO STITCHING

Constant accuracy across any measurement size

1 SCAN

TEST TIME

6 sec per scan

- + 4 sec displacement & stitching
- = 10 sec/scan x 6188 scans
- = **61860 seconds** (≈ 17 hours)

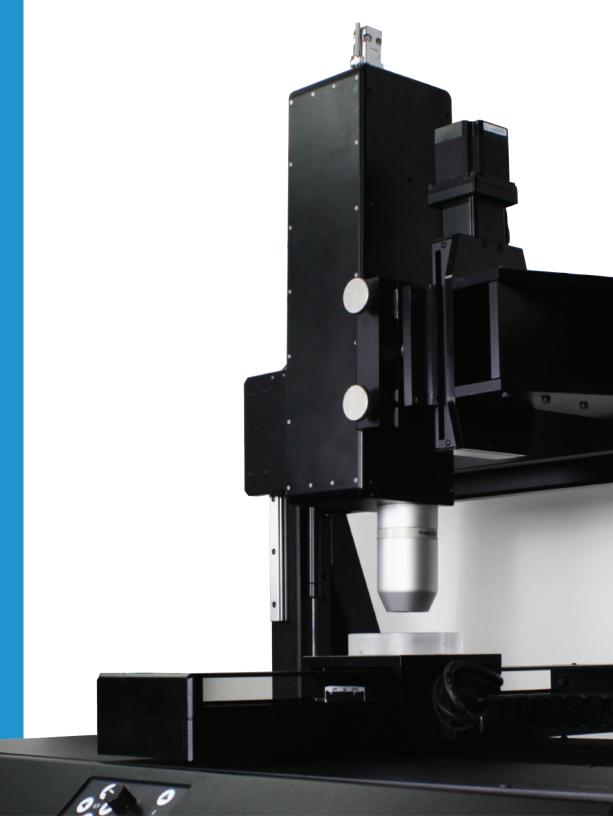


Scan time (25 x 25 mm)

= 29.6 seconds

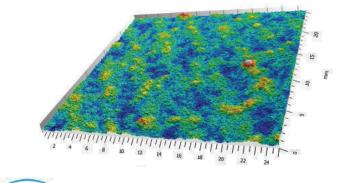
2090x FASTER

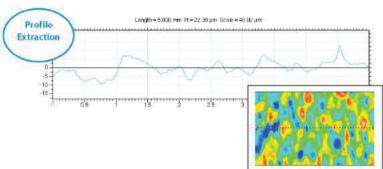
TESTING SOLUTIONS



ROUGHNESS | FINISH

- One second Ra measurement
- Any materials or surface complexity (3D or 2D)
- Automotive roughness finish standards





ROUGHNESS | FINISH ANALYSIS

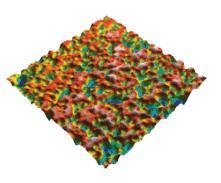
- Ra | Sa profile & surface average roughness
- Rq | Sq profile & surface rms roughness
- Sp | Sv maximum peak & pit height
- SKu | Ssk kurtosis & skewness of height distribution Sci & Svi core & valley fluid retention index

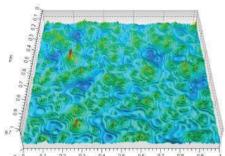
- Bearing ratio and index
- Sk kernel roughness depth
- Spk | Svk reduced peak height & valley depth
- Sr1 | Sr2 upper & lower material ratio

AND MORE

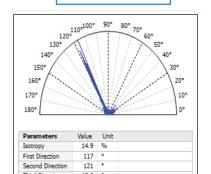
TEXTURE

- Isotropic & anisotropic surfaces
- Hills and valleys analysis





Texture Direction



TEXTURE ANALYSIS

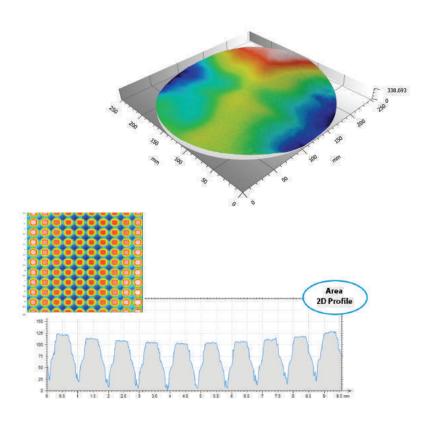
- 1st, 2nd and 3 rd direction
- % of periodicity

- Density of peaks
- Peak curvature (pointed or rounded)
- Average area of valleys & hills
- Average volume of valleys & hills

AND MORE

FLATNESS | WARPAGE

• Flatness < 1 µm over 500 mm with no correction



FLATNESS | WARPAGE ANALYSIS

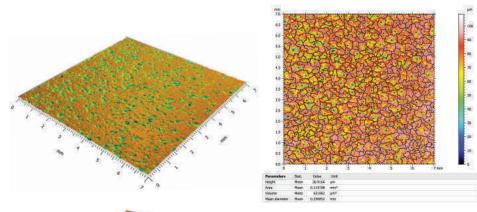
- 3D & 2D surface waviness & flatness
- Best polynomial match
- Material & bearing ratios
- Distance measurement

- FLTt peak to valley flatness deviation of the surface
- FLTp peak to reference flatness deviation
- FLTv reference to valley flatness deviation
- FLTq rms flatness deviation

AND MORE

VOLUME | AREA

- Surface subtraction & volume lost
- Corrosion analysis
- Motif and grain analysis





VOLUME | AREA ANALYSIS

- Volume of void, hills or valleys
- Sdar | Spar developed surface area & projected area
- Volume of void & material from given height
- Map area above or below given heights (%,um²)
- Mean thickness of void & material from given height

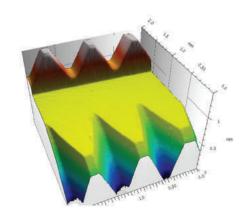
- # of grains & average size
- Area & perimeter of grains
- Height, area, volume of motifs
- Max and min pitch of motifs

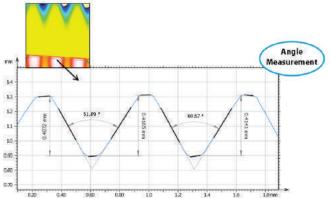
AND MORE

GEOMETRY AND SHAPE

- Direct comparison to CAD geometry
- Curvature, radius, angles
- · Lateral dimension
- Drill bit studies
- Cutting tools studies







GEOMETRY AND SHAPE ANALYSIS

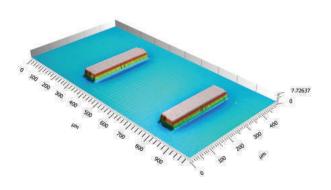
- Radius of curvature
- Relative angle measurement
- Distance measurement
- Mean diameter

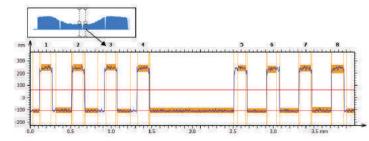
- Contour analysis
- Rake and wedge angle of drill bit
- K symmetry of cutting edge
- S alpha and gamma dist apex to end of clearance & rake roundness

AND MORE

STEP HEIGHT | THICKNESS

- Measure through transparent materials
- Transparent film and coating thickness down to 20nm
- Steps from 20nm to 25mm





STEP HEIGHT | THICKNESS ANALYSIS

• Point to point

• 3D or 2D map of thickness

• Point to plane

- Thickness distribution curve
- Maximum, minimum and mean heights

AND MORE

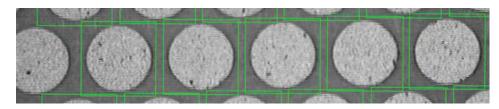
MICROSCOPE VIDEO IMAGING

Available on: **ST400, ST500, AFMPRO, & HS2000**

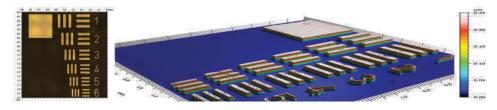
- Ultra zoom lens with coax lighting & detent
- Large area stitching capability
- Color video camera (1200x1600)
- Maximum magnification of 8000X
- Three positions turret (optional)



Broadview map selection tool



PRVision for machine vision capability



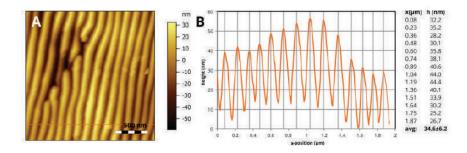


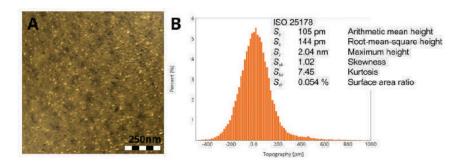


ATOMIC FORCE MICROSCOPE

Available on: AFMPRO

- Scan of XY 110μm | high resolution XY 25μm
- Lateral resolution 1.7nm
- Static, dynamic and extended modes
- Max Z range 22μm | 5μm
- Integrated video camera
- AFM to/from indenter position or video imaging with accuracy of $< 0.2 \mu m$







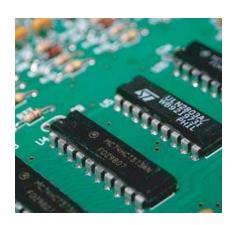
ADVANCED AUTOMATION



VISIT OUR APPLICATION NOTES LIBRARY

nanovea.com/app-notes

Nanovea Optical Profilers measure any material with a wider range of measurement than any other Profilometer.



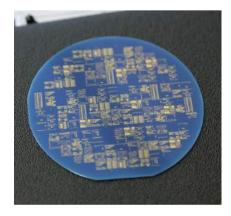














| BASE | Jr25 | Jr100 | PS50 | ST400 | ST500 | HS2000 |
|---|----------------|----------------------|----------------|-----------------------|-----------------------|------------------------|
| Туре | — Portable —— | Portable & Fast — | Compact | Standard | ———— Large Area — | Zero Noise / Flatness |
| X-Y Stage Travel ———— | 25 x 25mm —— | _100 x 100mm | 50 x 50mm | 200 x 150mm | 400 x 400mm _ | 400 x 500mm |
| Z Axis ———— 30 | mm Manual —— | 25mm Manual — | — 30mm Manual | 50mm Motorized | — 50mm Motorized – | 100mm Motorized |
| Maximum X-Y Speed ——— | —20 mm/s — | 20 mm/s | 20mm/s | 40mm/s | 200mm/s _ | 500mm/s |
| System Dimensions —— 20 | x 30 x 17cm | 44 x 49 x 32cm — | 38 x 33 x 43cm | ——— 62 x 62 x 82cm | ——— 97 x 72 x 92cm – | ——— 101 x 106 x 195cm |
| Rotational Options ———— | N/A | N/A | N/A | ——— Stage or Cylinder | — Stage or Cylinder – | Software |
| Video Microscope ———— | N/A | N/A | N/A | Available | ————— Available — | ———— Available |
| Max Sample Weight ———— | No Limit | No Limit — | 8Kg | 23Kg | 34Kg _ | 34Kg |
| High Speed Line Sensor —— | | | | | | |
| Customizable — 50mm | Stage Travel — | N/A — | N/A | 4 axis & AFM | 4 axis _ | — 400 x 750mm & 5 axis |
| Materials Types — A Max Surface Angle — U Max Vertical Resolution — 1 | p To 87° | k, Transparent, & Re | flective | nanove | ea.com/profilom | eters |
| STANDARD SENSOR (Singe | Point) PS1 | PS2 | | PS3 PS4 | PS5 | PS6 |
| Max Height Range | | | | 1.1mm 3.5n | | m 25mm |
| Working Distance — | | | | 12.0mm — 16.2 | | |
| Lateral Accuracy (X-Y) | 0.9μm | 1.2µ | m | 2.0μm — 3.0μ | ım ——— 7.0μn | n ———— 8.0μm |
| Height Repeatability (Ra) * – | 1.2nm | 2.2n | m ——— : | 3.4nm — 17n | m 31nm | 1 ———— 41nm |
| HIGH SPEED SENSOR (192 P | oints) | LS1 | | LS2 | | LS3 |
| Max Height Range ——— | | 200μm | | 0.95mm _ | | 3.9mm |
| Working Distance ——— | | 5.3mm — | | — 18.5mm ————— | | |
| Height Repeatability (Ra) * — | | 14nm | | 21nm | | 70nm |
| Line Width — | | 0.96mm | | 1.91mm — | | 4.78mm |
| Pitch ———— | | — 5μm ——— | | 10μm | | 25μm |
| Lateral Accuracy of each poir | nt | · | | 2μm | | 5μm |
| Acquisiton Rate (points per s | econd) — | — 384KHz ——— | | 384KHz — | | 384KHz |

^{*} Fixed point on glass, average height variation for 1200points (100 sampling)



N Today's Standard For Tomorrow's Materials.

NANOVEA instruments can be found in renowned education and industrial organizations around the world.

From aerospace applications to medical devices, thousands of clients at the frontiers of the most demanding industries, with no room for error, rely on our instruments' unmatched accuracy and technical superiority.

















